

## IN THE CLAIMS

1. (Currently amended) ~~A metallization structure in~~ Aa multilayer stack comprising a dielectric layer and one or more surrounding dielectric layers situated above or below the dielectric layer, a dielectric constant of the dielectric layer being greater than a dielectric constant of the surrounding dielectric layers, and a metallization structure which is arranged on the dielectric layer and is arranged at a distance from a ground electrode, characterized in that ~~wherein~~ the metallization structure has a capacitor electrode (22) and a line (24) that acts as a coil, where the capacitor electrode (22) and the line (24) are arranged in a common plane which lies parallel to the ground electrode (30) at a distance  $h_1$ , and in that ~~wherein~~  $w/h_1 > 3$ , where  $w$  is the width of the line (24).

2. A metallization structure as claimed in claim 1, ~~characterized in that~~ wherein a second ground electrode (32) is provided, the plane comprising capacitor electrode (22) and line (24) being arranged parallel to said second ground electrode at a distance  $h_2$ , and in that the plane comprising capacitor electrode (22) and line (24) lies between the first and second ground electrodes (30, 32), where  $w/h_2 > 3$ .

3. (Canceled)

4. (Canceled)

5. (Currently amended) A multilayer stack as claimed in claim 23, ~~characterized in that~~ wherein the following applies in respect of the layer thickness ( $d_{\text{medium}}$ ) of the

dielectric layer (14):

$$\frac{\epsilon_{\text{medium}} \cdot d_{\epsilon}}{\epsilon \cdot d_{\text{medium}}} > 5$$

wherein the dielectric constant of and a thickness of the dielectric layer are  $\epsilon_{\text{medium}}$  and  $d_{\text{medium}}$ , respectively, and the dielectric constant of and a thickness of the surrounding dielectric layers are  $\epsilon$  and  $d_{\epsilon}$ , respectively.

6. (Currently amended) A multilayer stack as claimed in claim 3 comprising one or more additional metallization structures in the plane, characterized in that~~wherein~~

$$\frac{\epsilon_{\text{medium}} \cdot d_{\text{min}}}{\epsilon \cdot d_{\text{medium}}} > 7,$$

where  $d_{\text{min}}$  is the minimum distance to ~~the next~~ a nearest metallization structure in the plane.

7. (Currently amended) A multilayer stack as claimed in claim 3, ~~characterized in that~~wherein it the multilayer stack comprises magnetic layers.

8. (Currently amended) A multilayer stack as claimed in claim 23, produced in a multilayer laminate process.

9. (Currently amended) A multilayer stack as claimed in claim 23, produced in an LTCC process.

10. (Canceled)